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Docket No. YOR919990408CIP/YOR129 CIP

B 1 FW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Cabral, Jr., et al.

Serial No.: 09/902,483

Filing Date: July 11, 2001

Group Art Unit: 2813

Examiner: Erik J. Kielin

For: SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY
CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK MOSFETS
AND FOR SHALLOW JUNCTIONS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRIOR ART SUBMISSION

Sir:

For the possible benefit of anyone subsequently evaluating the scope and/or validity of the above patent, it is respectfully requested that the following references cited in the corresponding Patent Application, be placed in the file wrapper:

1. U.S. Patent No. 6,072,222
2. U.S. Patent No. 6,214,679 B1

The undersigned has not reviewed the teachings of these references in detail and thus makes no representations concerning their relevancy or materiality.

Respectfully submitted,



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Date: 12/17/04

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